WHAT IS CLAIMED IS:

- 1. A polishing pad for chemical-mechanical polishing comprising a porous foam having a multi-modal pore size distribution, wherein the multi-modal distribution has about 20 or fewer pore size maxima.
- 2. The polishing pad of claim 1, wherein the multi-modal pore size distribution is a bimodal pore size distribution.
- 3. The polishing pad of claim 2, wherein the bimodal distribution has a first pore size maximum of about 50 μm or less and a second pore size maximum at about 50 μm or more.
- 4. The polishing pad of claim 2, wherein the bimodal distribution has a first pore size maximum at about 20 μ m or less and a second pore size maximum at about 20 μ m or more.
- 5. The polishing pad of claim 1, wherein the porous foam comprises a polymer resin selected from the group consisting of thermoplastic elastomers, thermoplastic polyurethanes, polyolefins, polycarbonates, polyvinylalcohols, nylons, elastomeric rubbers, styrenic polymers, polyaromatics, fluoropolymers, polyimides, cross-linked polyurethanes, cross-linked polyolefins, polyethers, polyesters, polyacrylates, elastomeric polyethylenes, polytetrafluoroethylenes, polyethyleneteraphthalates, polyimides, polyaramides, polyarylenes, polystyrenes, polymethylmethacrylates, copolymers and block copolymers thereof, and mixtures and blends thereof.
- 6. The polishing pad of claim 5, wherein the polymer resin is a thermoplastic polyurethane.
- 7. The polishing pad of claim 6, wherein the thermoplastic polyurethane has a Melt Index of about 20 or less, a weight average molecular weight (M_w) of about 50,000 g/mol to about 300,000 g/mol, and a polydispersity index (PDI) of about 1.1 to about 6.
- 8. The polishing pad of claim 6, wherein the thermoplastic polyurethane has a Rheology Processing Index (RPI) of about 2 to about 8 at a shear rate (γ) of about 150 l/s and a temperature of about 205 °C.

- 9. The polishing pad of claim 6, wherein the thermoplastic polyurethane has a Flexural Modulus of about 350 MPa to about 1000 MPa.
- 10. The polishing pad of claim 6, wherein the thermoplastic polyurethane has a glass transition temperature of about 20 °C to about 110 °C and a melt transition temperature of about 120 °C to about 250 °C.
- 11. The polishing pad of claim 1, wherein the porous foam comprises a water-absorbent polymer.
- 12. The polishing pad of claim 11, wherein the water-absorbent polymer is selected from the group consisting of cross-linked polyacrylamide, cross-linked polyacrylic acid, cross-linked polyvinyl alcohol, and combinations thereof.
- 13. The polishing pad of claim 1, wherein the porous foam comprises particles selected from the group consisting of abrasive particles, polymer particles, composite particles, liquid carrier-soluble particles, and combinations thereof.
- 14. The polishing pad of claim 13, wherein the porous foam further comprises abrasive particles selected from the group consisting of silica, alumina, ceria, and combinations thereof.
- 15. The polishing pad of claim 1, wherein the porous foam has a void volume of about 25% or less.
- 16. The polishing pad of claim 1, wherein the porous foam comprises closed cells.